Application Number:	10	10598502						
	_							
Filing Date:	01-	01-Sep-2006						
Title of Invention:		Sputtering target with few surface defects, and surface processing method thereof						
First Named Inventor/Applicant Name:	Yu	Yuichiro Nakamura						
Filer:	Wi	William Bak						
Attorney Docket Number:	00	OGOSH60USA						
Filed as Large Entity								
U.S. National Stage under 35 USC 371 Fil	ing Fee	s						
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)			
Basic Filing:								
Pages:								
Claims:								
Independent claims in excess of 3		1614	1	220	220			
Miscellaneous-Filing:			'					
Petition:								
Patent-Appeals-and-Interference:								
Post-Allowance-and-Post-Issuance:								

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 1 month with \$0 paid	1251	1	130	130
Miscellaneous:				
	Tot	350		